



This is intended as a full and complete response to the Office Action dated February 4, 1999. Claims 1-20 are restricted in this application, and claims 1-18 and 20 are provisionally elected with traverse for consideration by the Examiner. Claims 1-20 are restricted by the Examiner as follows:

Group I. Claim 19 drawn to an apparatus, classified in class 29, subclass 25.01.

Group II. Claims 1-18 and 20, drawn to a method of making a semiconductor

device, classified in class 438, subclass 260.

Method claims 1-18 and 20 are restricted by the Examiner from apparatus claim 19 on grounds that the apparatus of claim 19 can be used to practice a materially different process, for example, a process that deposits metal patterns on a substrate board for receiving an IC chip, or a process that forms contacts for field emission cathode rays. Applicants respectfully traverse this restriction on grounds that the Examiner does not state any basis for finding that the identified processes are materially different from the processes claimed by Applicants. The Examiner asserts that the additional processes can be run in the same chamber, and provides no information about differences between the processes to support a finding that the processes are materially different from the elected claims. Thus, the Examiner fails to properly restrict claim 19 from claims 1-18 and 20. Applicants respectfully request withdrawal of the restriction requirement to allow prosecution of claims 1-20.

Respectfully submitted,

Keith M. Tackett

Reg. No. 32,008

PATTERSON & ASSOCIATES 3040 Post Oak Blvd., Suite 1500

Houston, TX 77056

713/623-4844

ATTORNEY FOR APPLICANTS

٠٠٠٠.